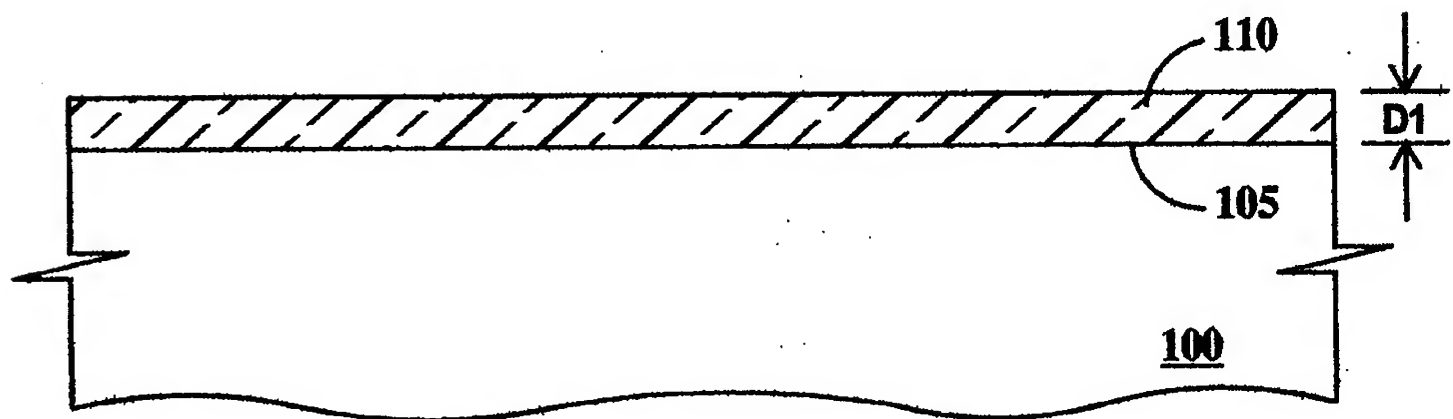
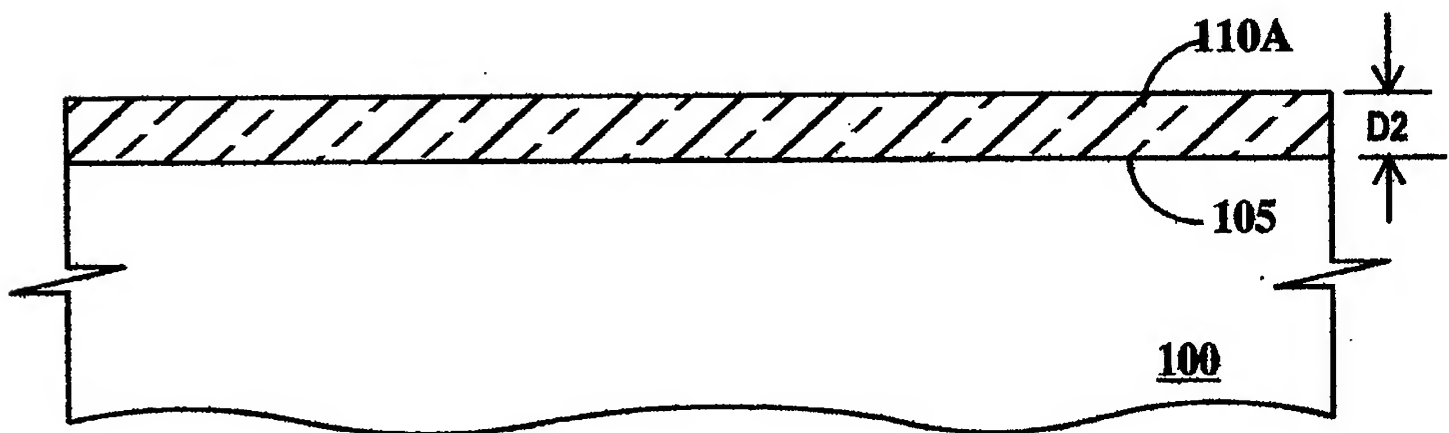


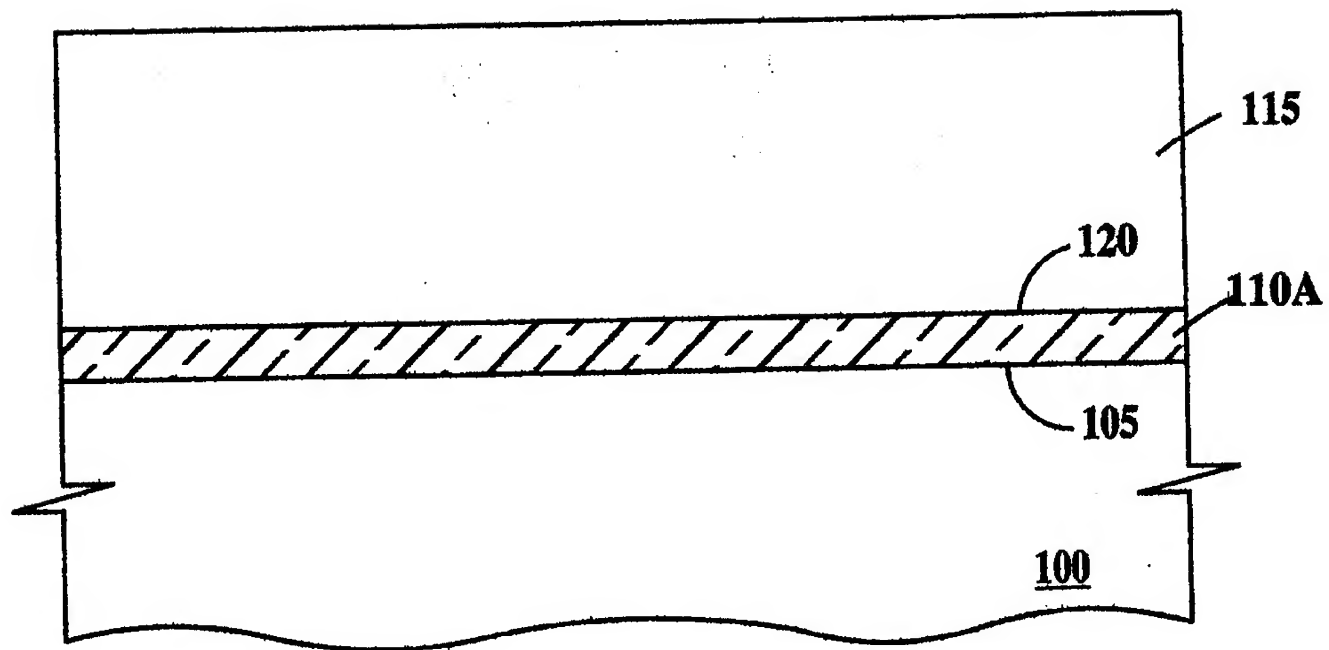
**FIG. 1**



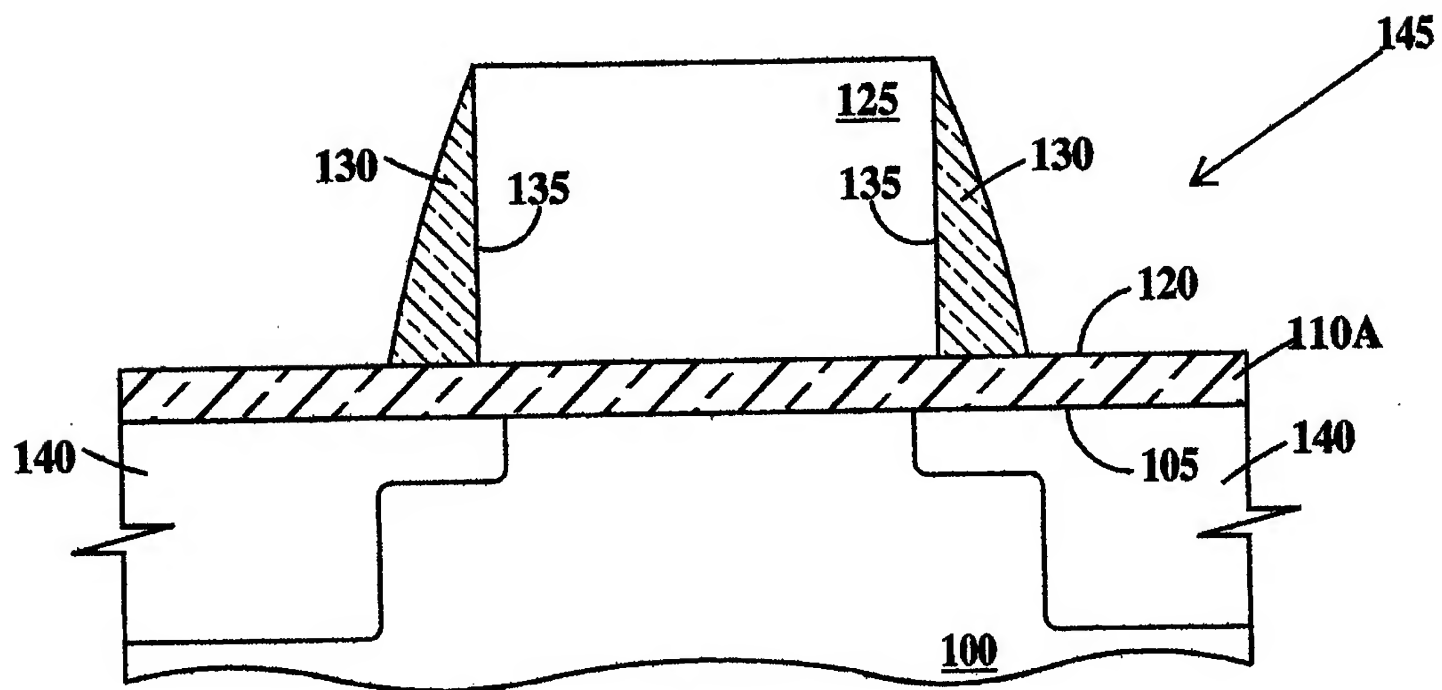
**FIG. 2**



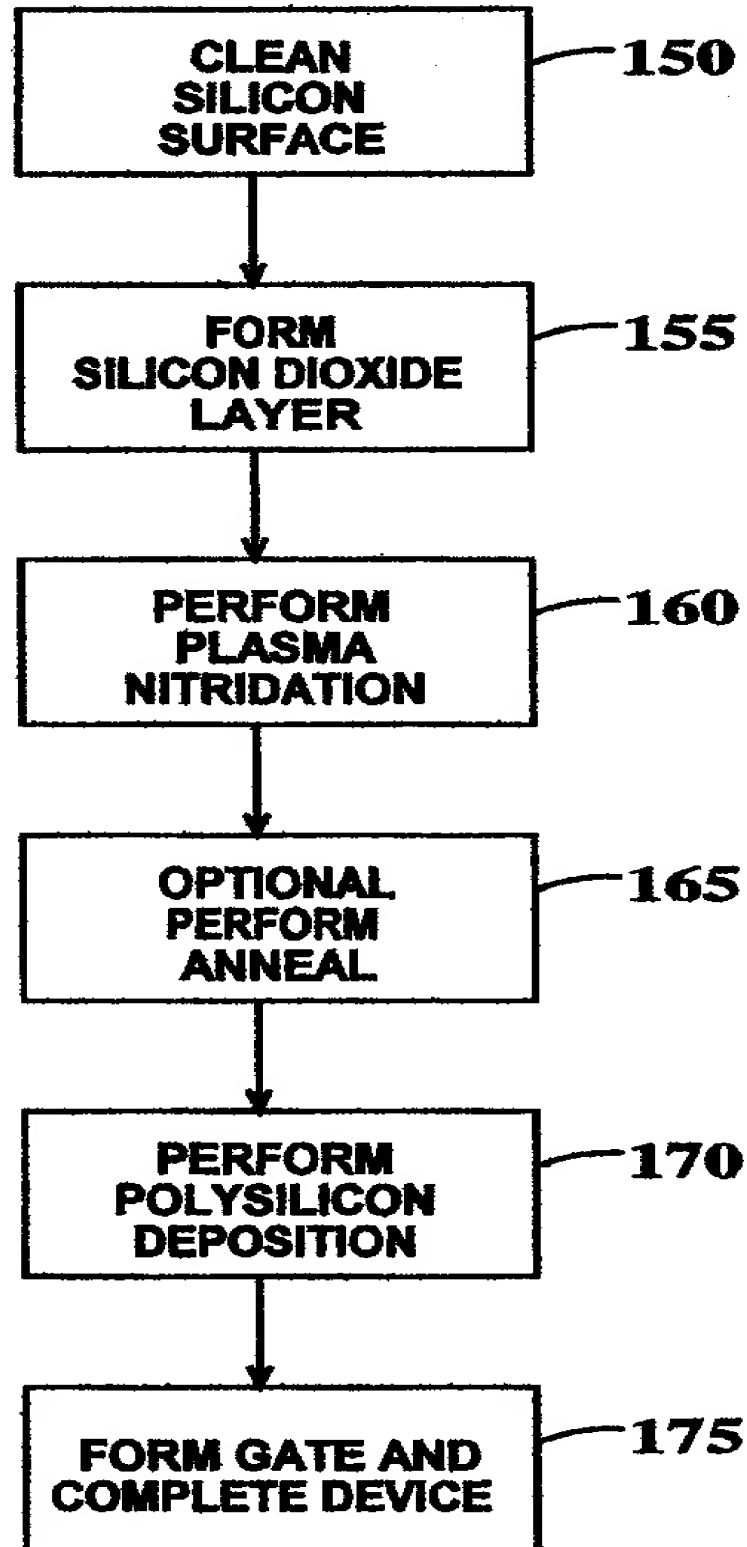
**FIG. 3**



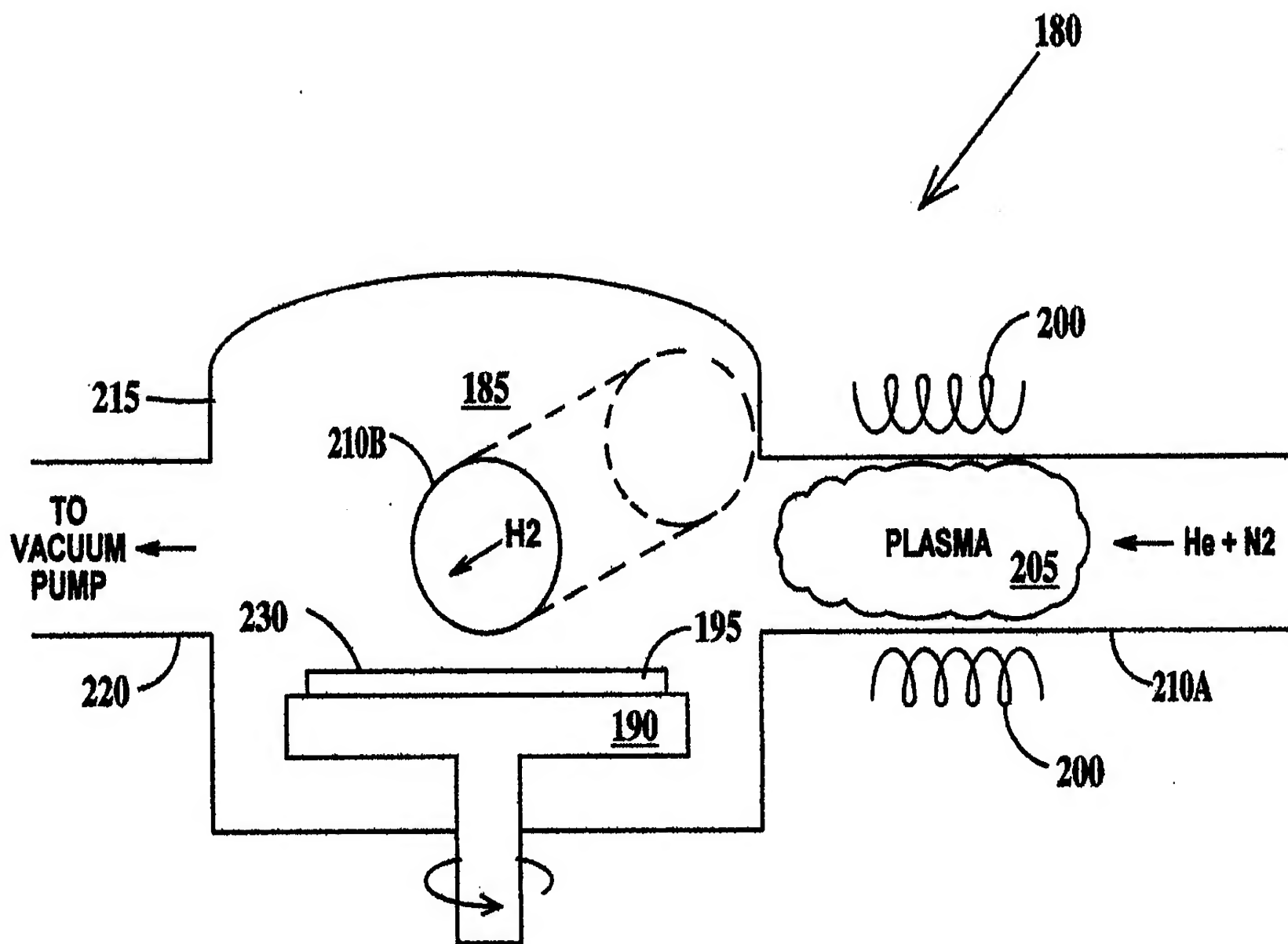
**FIG. 4**



**FIG. 5**

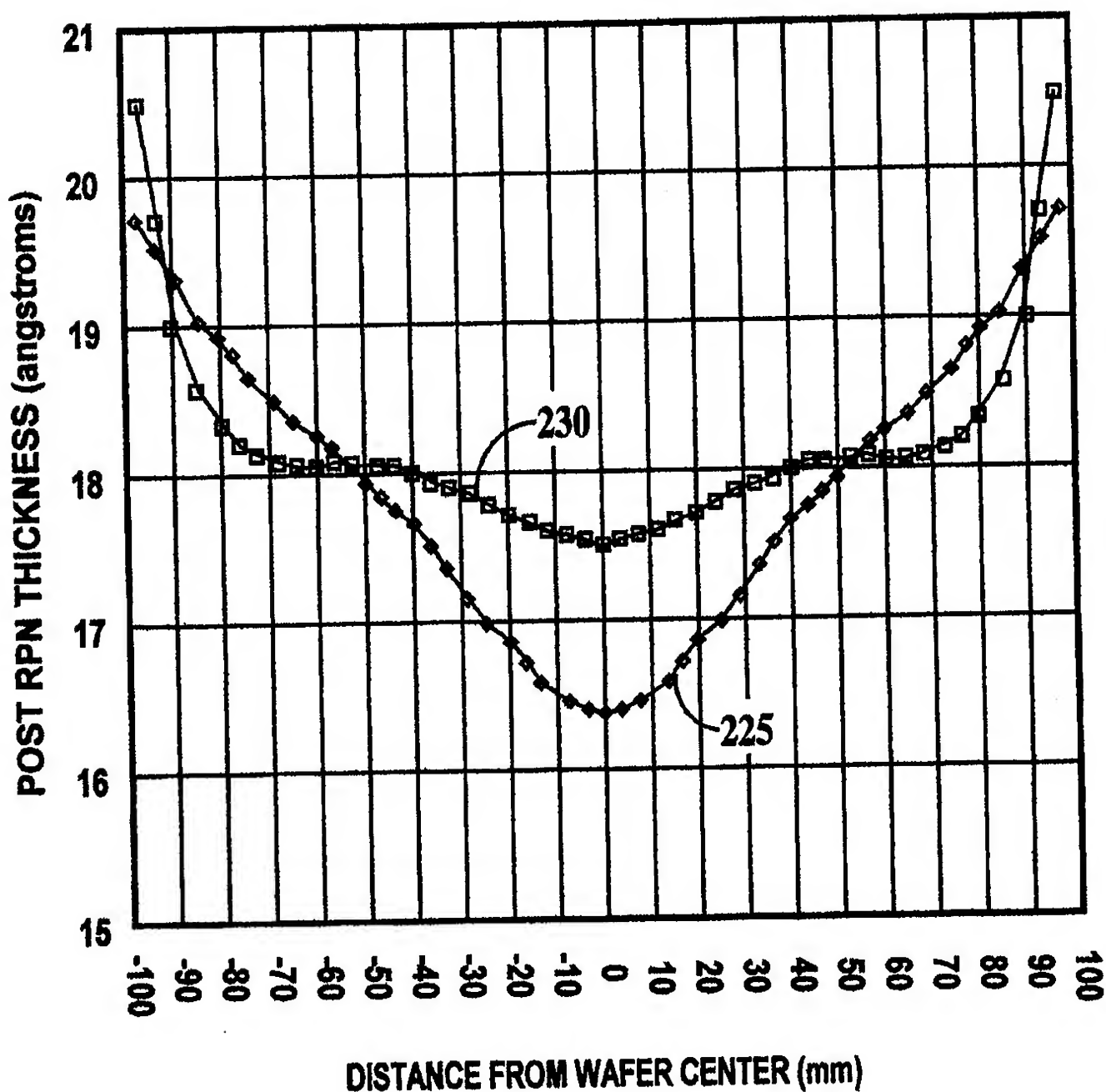


**FIG. 6**



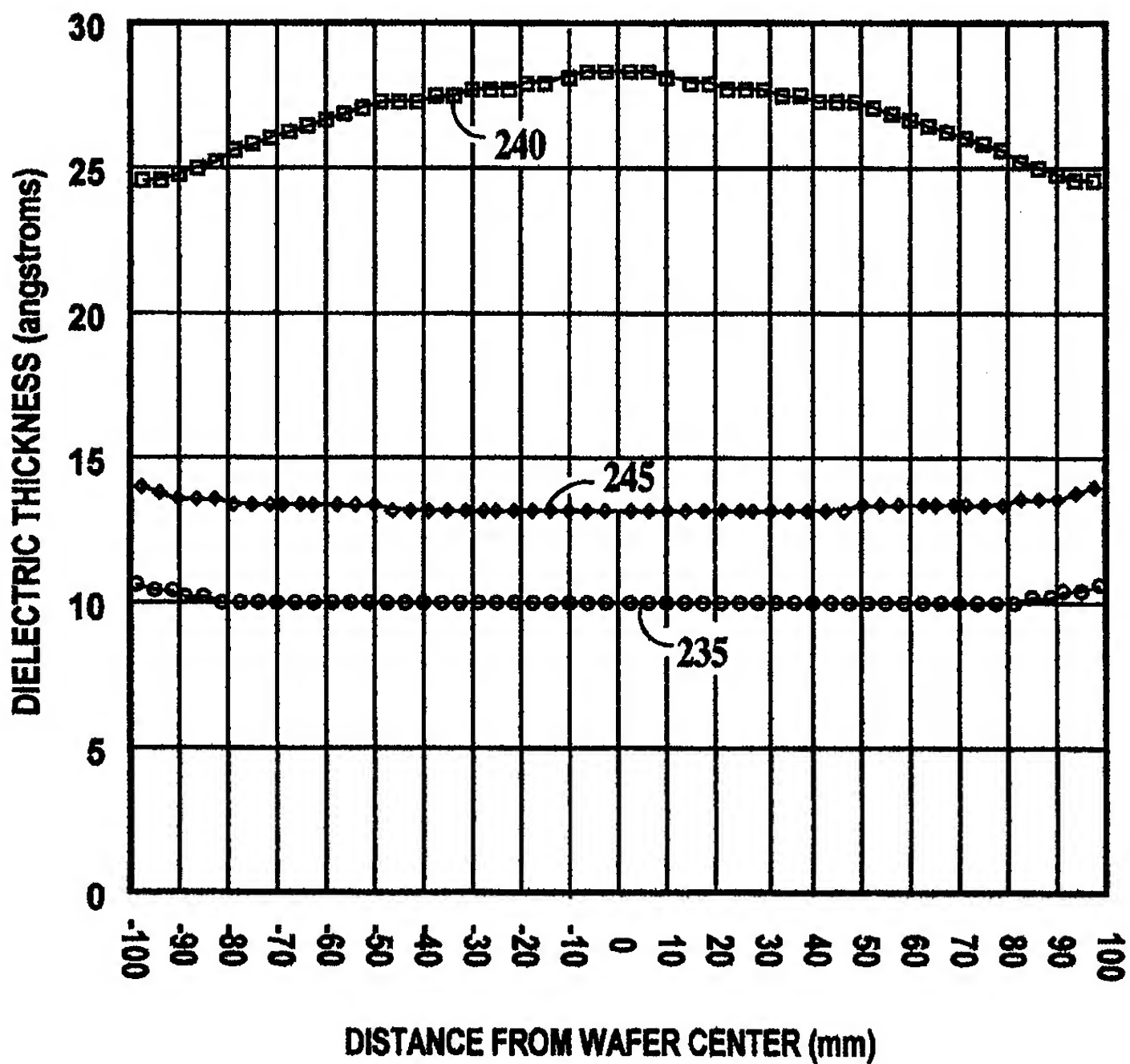
**FIG. 7**

**ACROSS WAFER THICKNESS UNIFORMITY  
POST REMOTE PLASMA NITRIDATION**

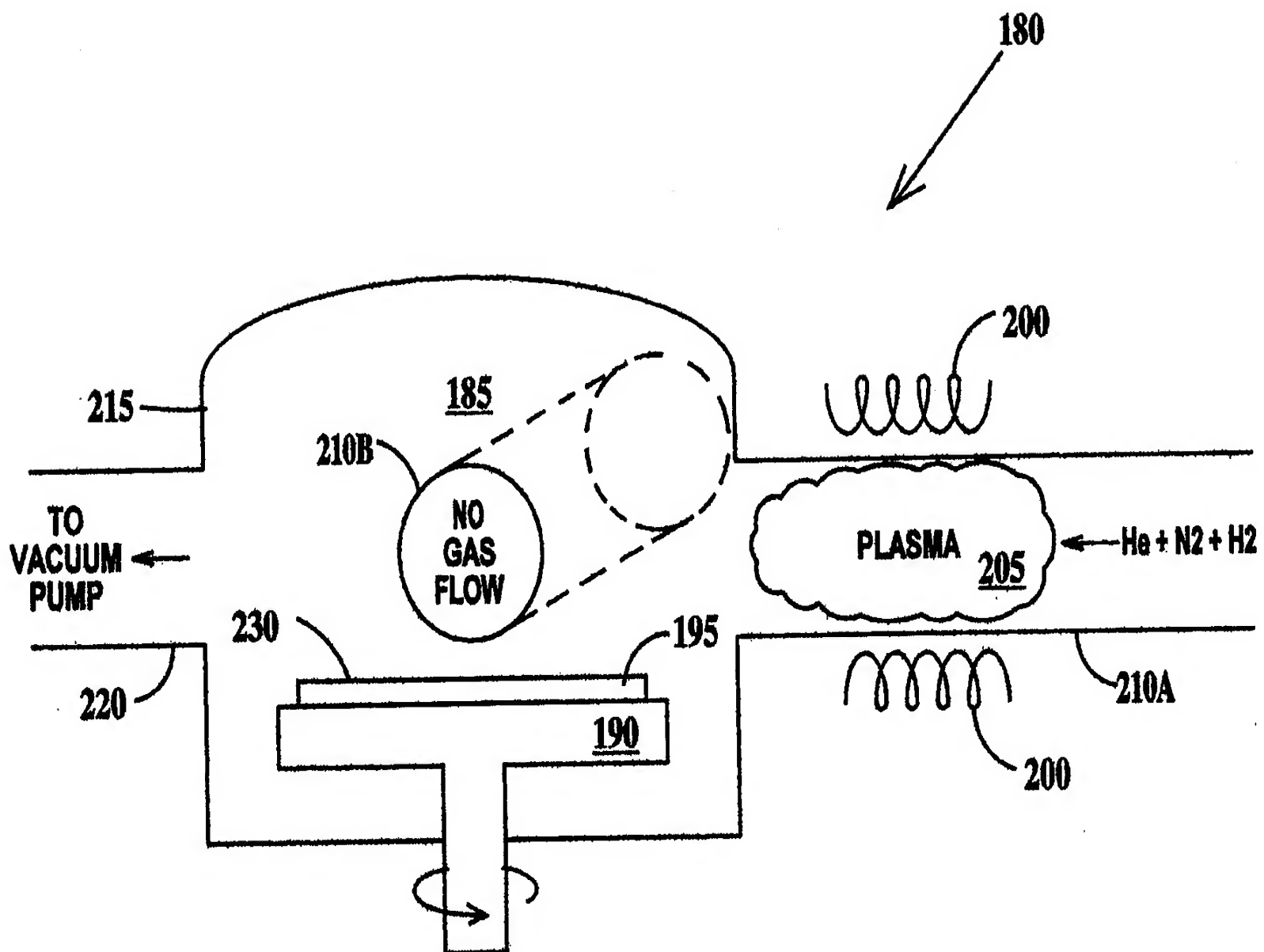


**FIG. 8**

**ACROSS WAFER THICKNESS UNIFORMITY  
POST REMOTE PLASMA NITRIDATION  
ON NATIVE OXIDE**



**FIG. 9**



**FIG. 10**